

5.3 Pore Etching

Most old pictures have not survived. Here is what I still have.

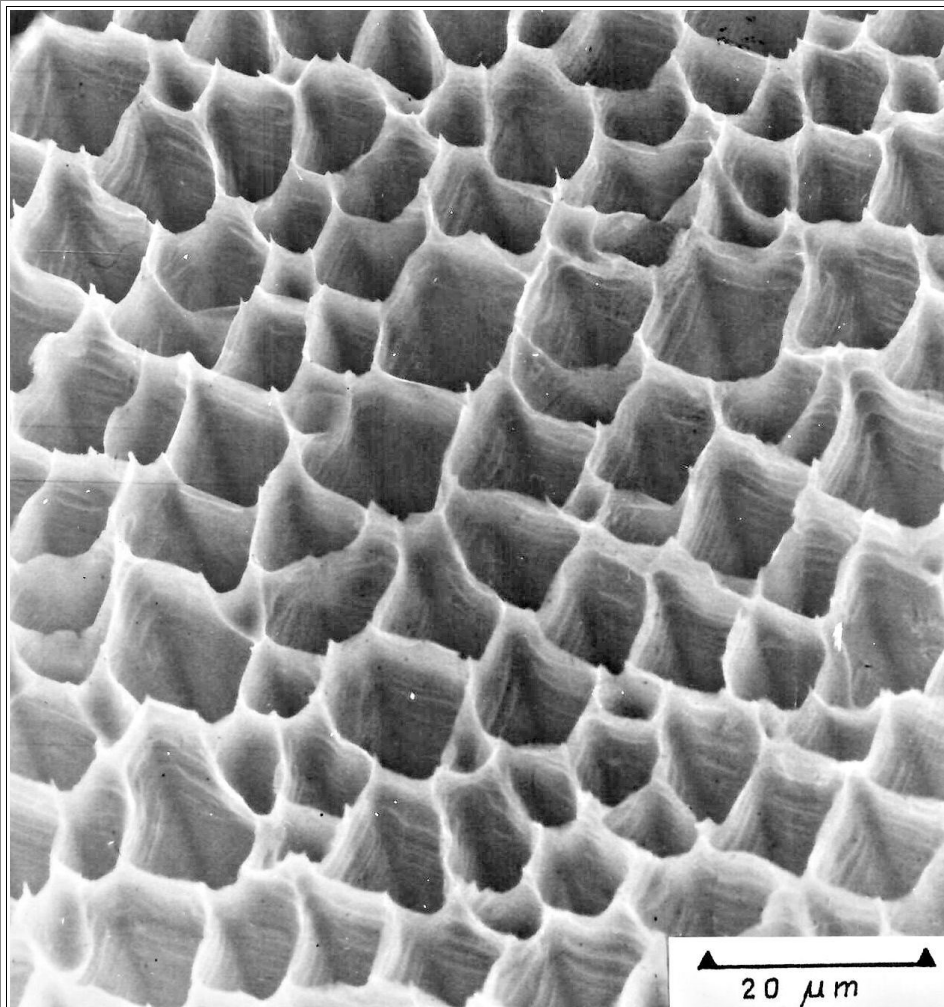
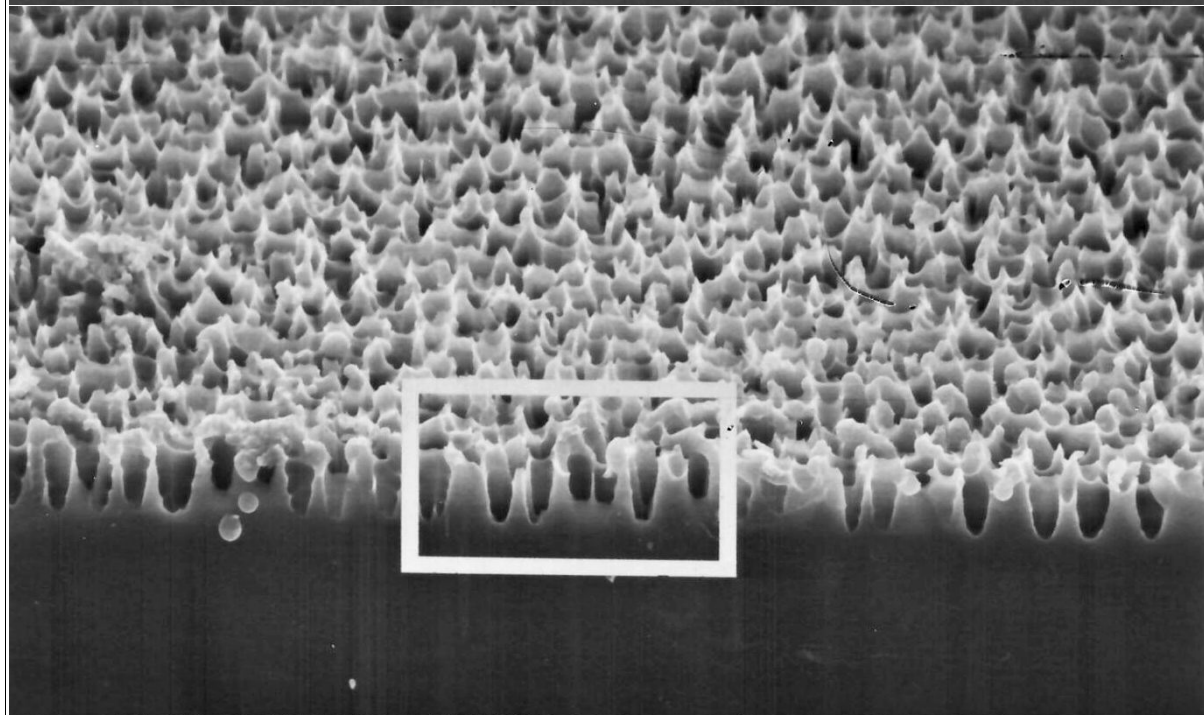
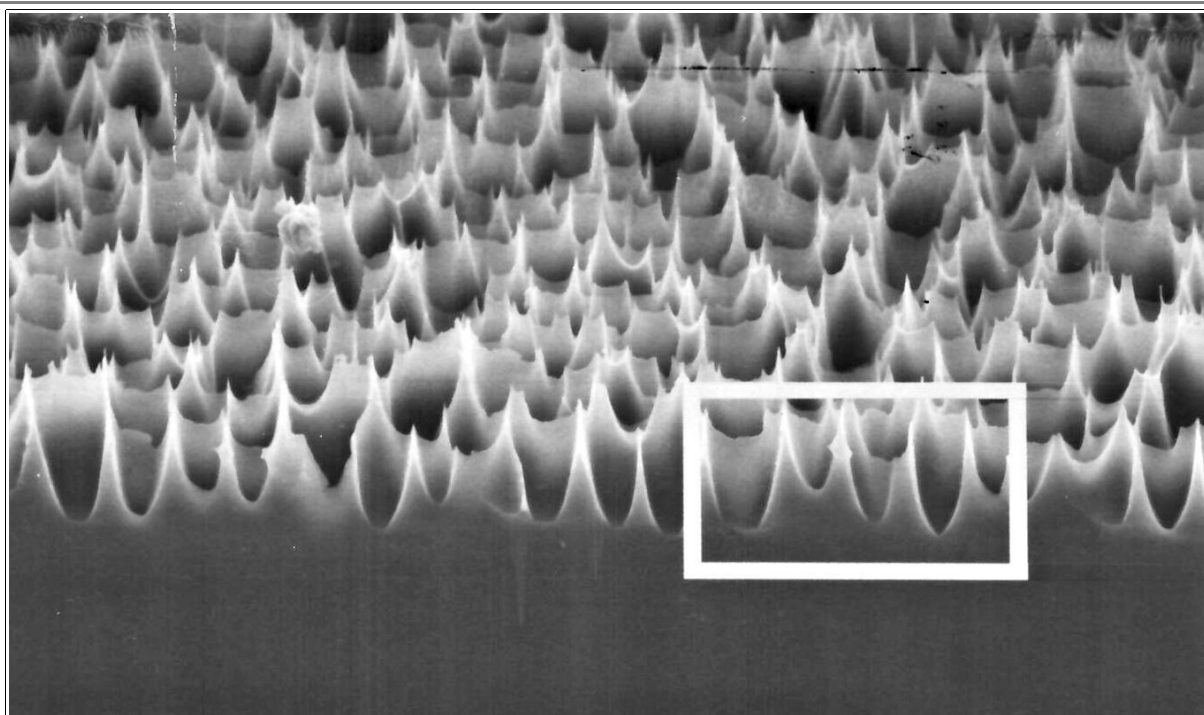


Fig. 7 in publication 67

Microstructure of n-type Si after prolonged etching with $I < I_{PSL}$



50 μm

Pictures not in publications
but relating to Fig. 3 in publication 60

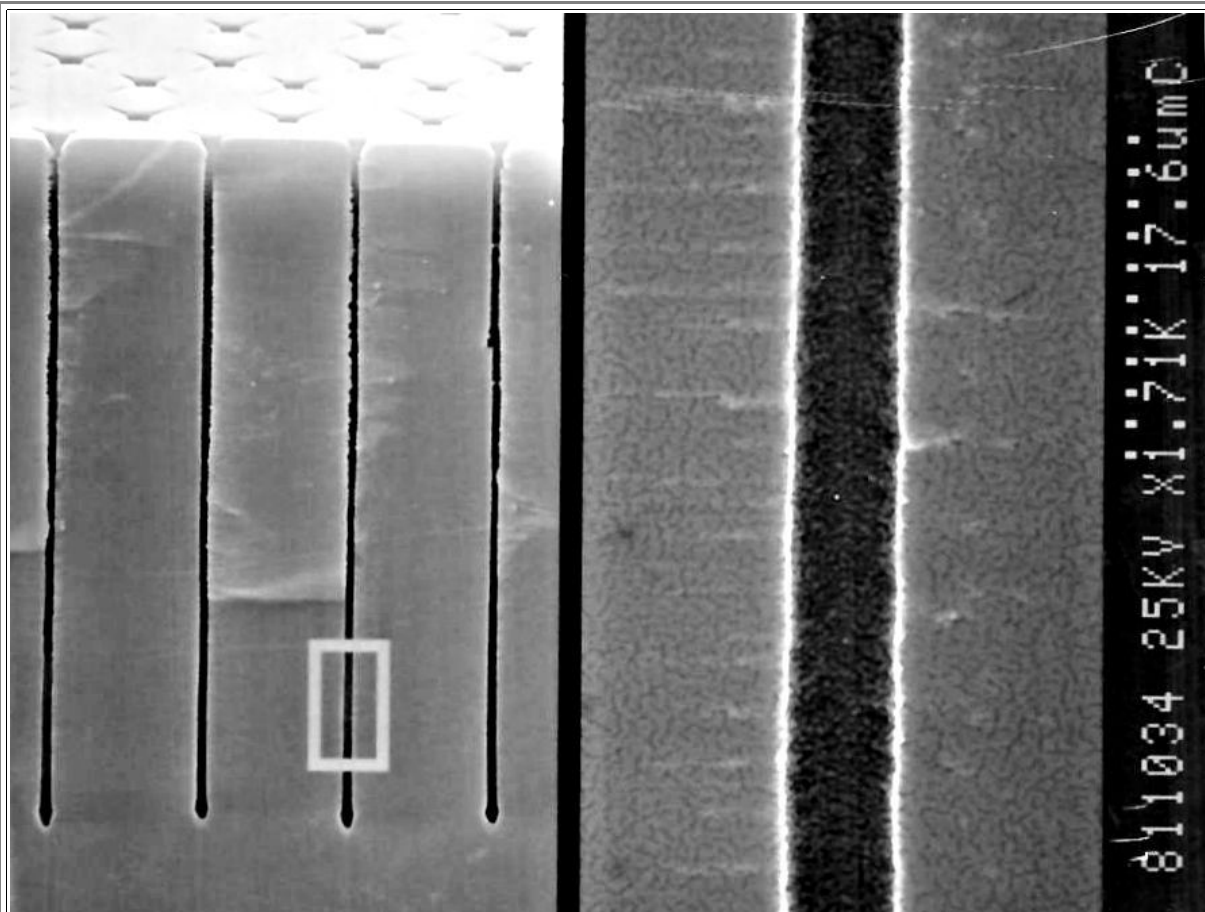
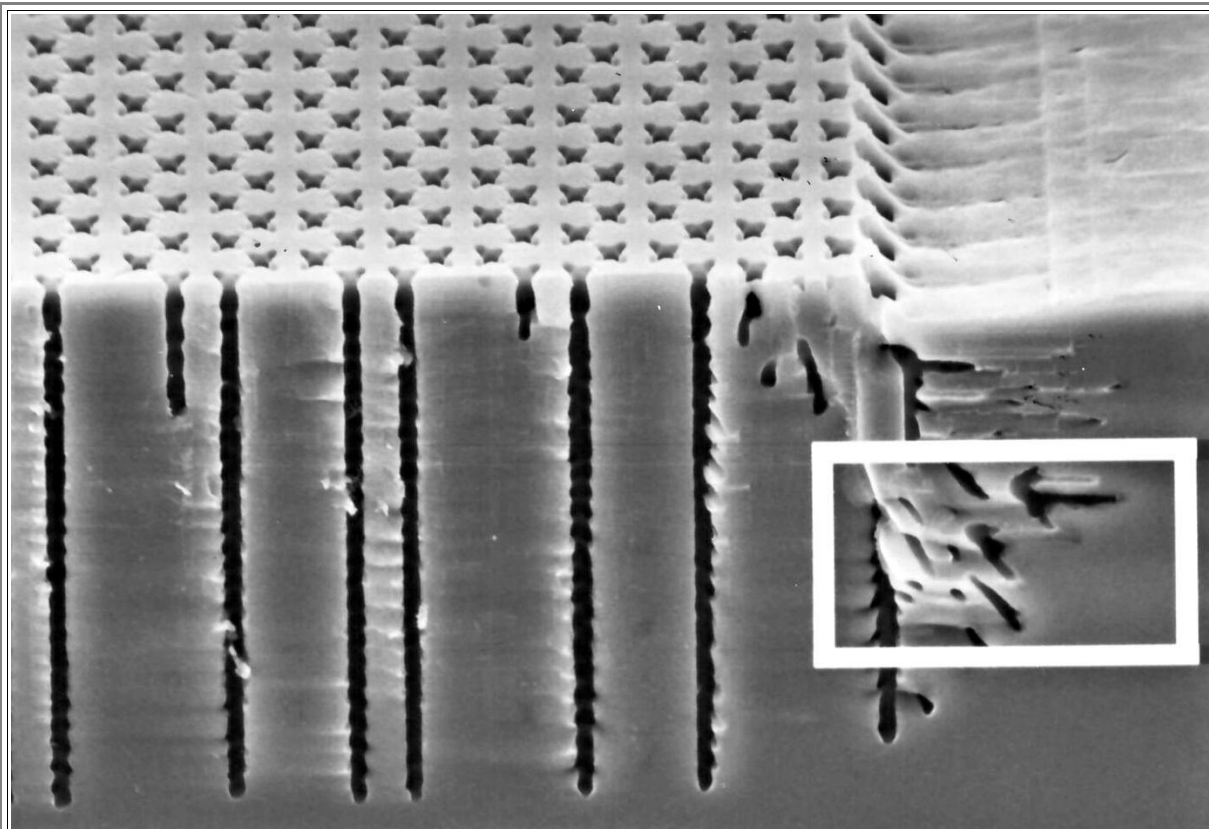


Fig 9 in publication 67 and relating to Fig 9 in 60

Fig. 9. SEM micrograph (cross section, 0°) of electrochemically etched trenches with high aspect ratio. (B2 sample, 10V, 30 min, 330 pA/trench; all three samples: photocurrent adjusted by back side illumination, PSL removed by 10s in 10 w/o KOH.)

The picture from the full paper (ref, 60) follows



Pictures not in publications
but obviously related.